

Docket No.: FIS920000301US1  
CBLH/20136-00326-US1  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Patent Application of:  
Marie Angelopoulos, et al.

Application No.: TBA

Art Unit: 1752

Filed: Herewith

Examiner: R. Ashton

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For: RADIATION SENSITIVE SILICON-  
CONTAINING NEGATIVE RESISTS AND  
USE THEREOF

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**PRELIMINARY AMENDMENT**

**MS PATENT APPLICATION**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 9, 2003

Dear Sir:

**INTRODUCTORY COMMENTS**

Prior to examination on the merits and calculation of any fees for excess claims, please amend the above-identified U.S. patent application as follows:

**Amendments to the Specification** begin on page 2.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 3 of this paper.

**Remarks/Arguments** begin on page 6 of this paper.